



Att. Docket No. 10191/1690

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. Serial No. : 09/762,985 Confirmation No. 2674
Title : DEVICE AND METHOD FOR
ETCHING A SUBSTRATE USING
AN INDUCTIVELY COUPLED PLASMA
Applicant(s) : Volker BECKER et al.
Filed : May 8, 2001
TC/A.U. : 1763
Examiner : Luz L Alejandro Mulero
Docket No. : 10191/1690
Customer No. : 26646

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AMENDMENT AFTER A FINAL OFFICE ACTION

S I R:

In response to the Final Office Action mailed on August 21, 2003 (the two-month response date for which is October 21, 2003), please reconsider the above-identified application based on the following:

Amendments to the Claims are reflected in the listing of the claims which begins on page 2 of this paper.

Remarks begin on page 9 of this paper.

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